



SUB-WAVELENGTH OPTICS FOR MINIATURIZED SENSING AND IMAGING APPLICATIONS

**EPIC Technology Meeting on Photonics for Miniaturized Optics:
From Components to Use-cases at Sony DADC**
18-19 September 2024

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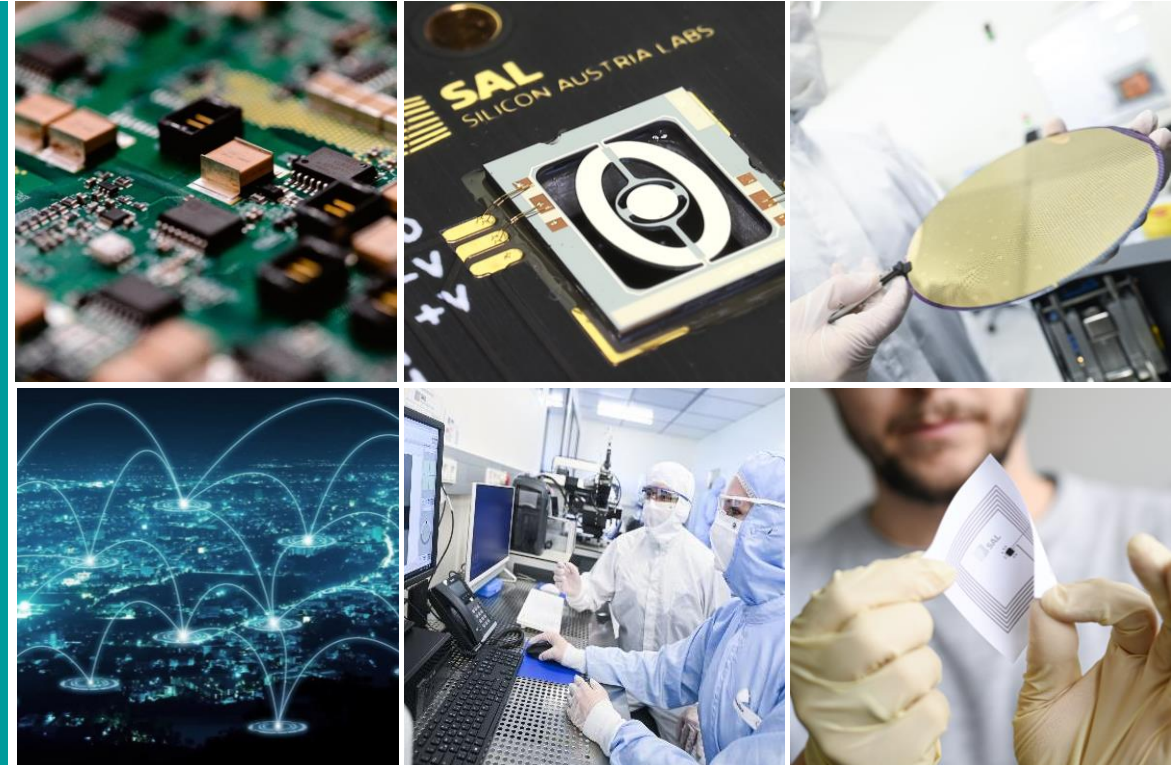
SILICON AUSTRIA LABS

What do we do?



Silicon Austria Labs (SAL), established in 2018, is a European **R&D center** with a focus on the development of efficient and trustworthy technologies in the field of **electronic systems**.

- Industry-oriented research
- R&D services
- Well-equipped research infrastructures
- Customized opportunities for cooperation



KEY FACTS*

Who we are

Founded: 2018



3

LOCATIONS

- Graz (HQ)
- Villach
- Linz



> 90

PARTNER NETWORK

- From Industry & Research



> 300

EXPERTS

- Experienced team
- 40 nations
- Multidisciplinary



184

PUBLICATIONS



5

SHAREHOLDER

- 50,1 % Republic of Austria (BMK)
- 24,95 % FEEI
- 10 % Styria (SFG)
- 10 % State of Carinthia
- 4,95 % Upper Austria (UAR)



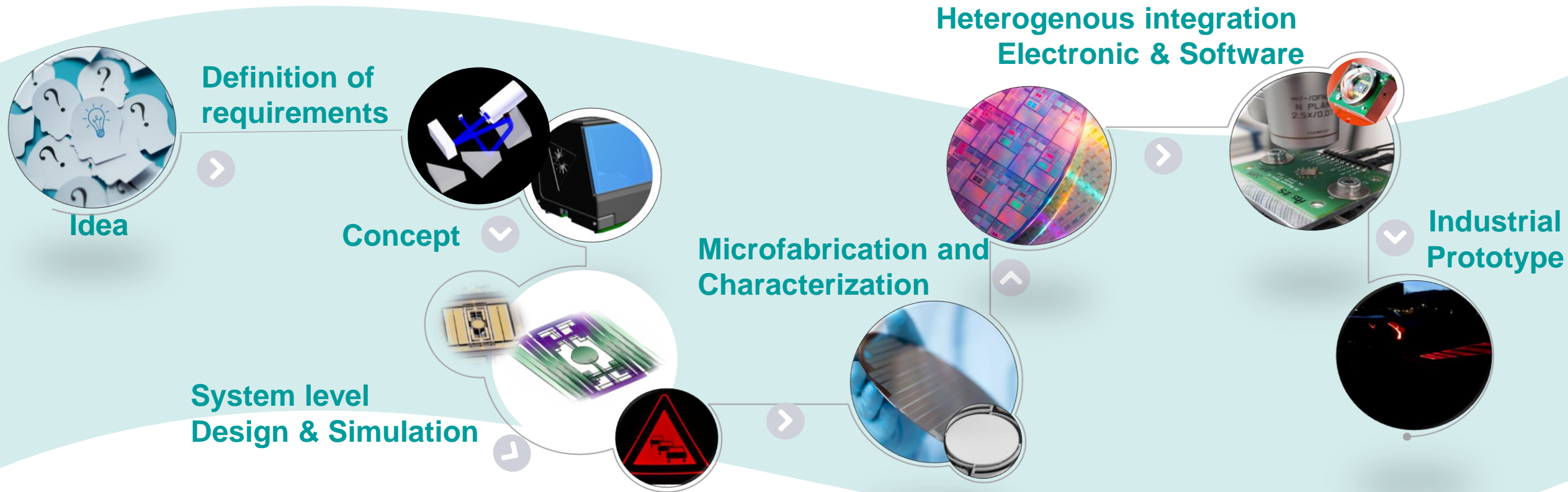
45 Mio. €

PROJECT VOLUME

- Total volume for research projects

SAL UNIQUE SELLING PROPOSITION FROM IDEA TO PRODUCT

Enabling quick and reliable technology implementation through a **full stack of competencies**:
an example for a MOEMS scanning micromirror for smart road lighting



SAL Divisions



**SENSOR
SYSTEMS**



**POWER
ELECTRONICS**



**INTELLIGENT
WIRELESS
SYSTEMS**



**MICRO-
SYSTEMS**



**EMBEDDED
SYSTEMS**

MICROSYSTEMS

The Microsystems Research Division is dedicated to pioneering advancements beyond current technological standards in novel micro-electro-mechanical systems (MEMS), MOEMS, integrated photonics, and integrated magnetics by synergizing advanced materials and fabrication technologies. Through close collaboration with industrial and scientific partners, SAL endeavors to innovate at every stage, from initial design and proof-of-concept to the development of product prototypes.

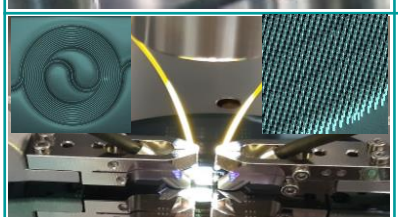
RESEARCH TOPICS



Piezoelectric Microsystem Technologies pioneers innovative MEMS solutions for miniaturized sensors, transducers, and acoustic wave resonators, establishing full stack development platforms for novel piezo MEMS systems.



Magnetic Microsystem Technologies focuses on the development and integration of magnets, sensors and spintronic devices into microsystems and their applications for magnetic position and orientation sensing.



Integrated Photonics Technologies specializes in advancing meta-optics and integrated photonic solutions tailored for compact, multifunctional sensors applicable across automotive, consumer electronics, communication sectors.

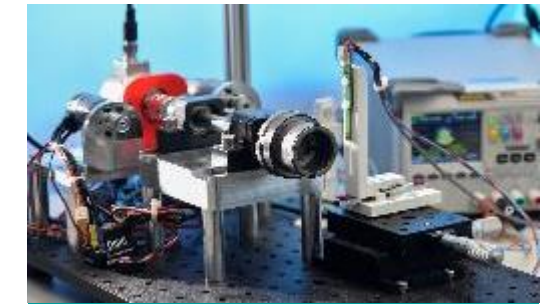


Thin-film Technologies specializes in solutions catering to the development, fabrication, and characterization of cutting-edge thin film technologies applied across piezo-electrics, photonics, magnetics, and electronics applications.

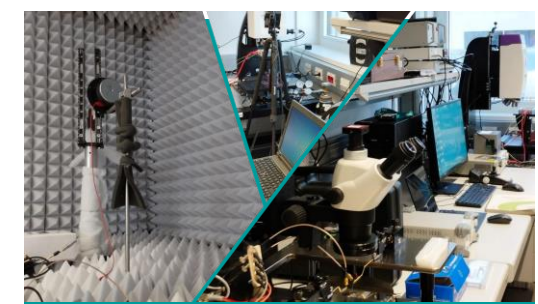
INFRASTRUCTURE



THIN FILM CLUSTER



MAGNETICS LAB



ACOUSTICS LAB



PHOTONICS LAB



SAL MicroFab

MICRO NANO FABRICATION CENTER



- To bridge the gap between R&D and high-volume manufacturing (HVM) with advanced prototyping, small series production and process transfer to industrial level
- To cooperate with global players on cutting-edge electronic based system applications
- To create synergy between scientific and industrial partners
- To become a key step in the idea to product competence

2016 → 2018 → 2020 → 2022 → 2023 → 2024 → 2026 → 2028 → 2030

SAL MicroFab Cleanroom I



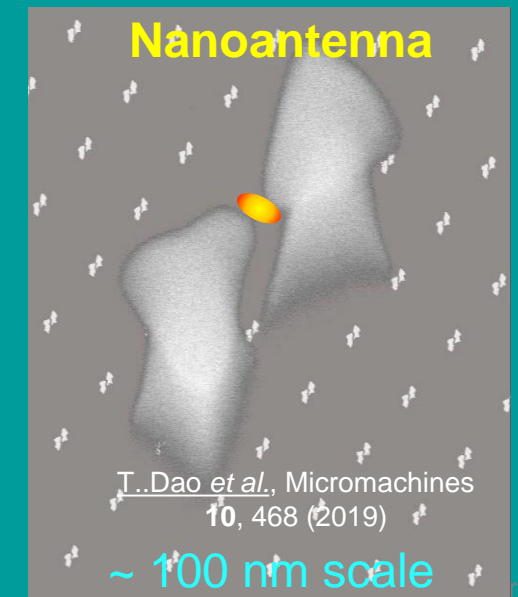
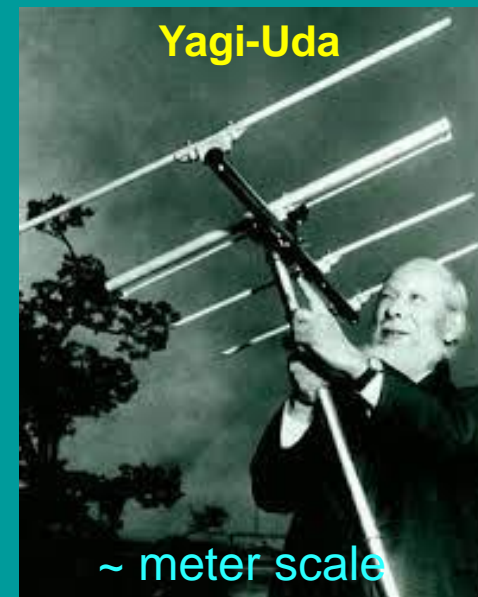
- 300 m² ISO 5
- Up to 8-inch process capability
- Micro and nano fabrication: M(O)EMS, RF filters, integrated photonics
- Characterization equipment

SAL MicroFab **NEW** Cleanroom II



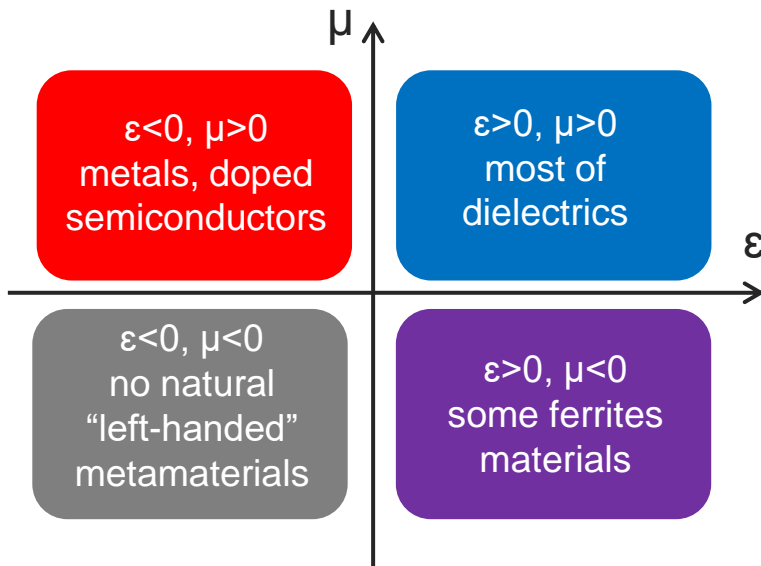
- 1100 m² ISO 4 / 5
- Focus on small series production
- Semi-automated – Technology transfer to HVM
- Front-end and Back-end (More than Moore)
- MEMS, PIC, Heterogeneous integration,

SUB-WAVELENGTH OPTICS – ENGINEERING LIGHT AT SUB-WAVELENGTH SCALES



METAMATERIALS

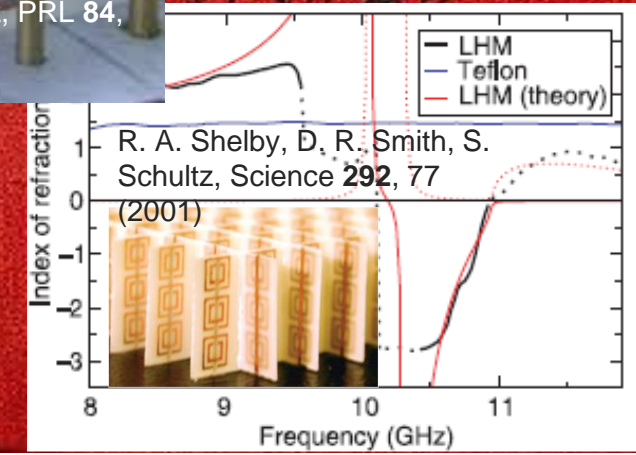
- ≡ “Left-handed” metamaterials: *Negative* permeability and permittivity → doppler effect, Cherenkov radiation and Snell’s law are inverted.
- ≡ Proposed by V. G. Veselago (1967); developed by D. R. Smith, W. J. Padilla, S. Schultz (2000); J. B. Pendry; V. Shalaev,
- ≡ Materials: Metals, hybrid metal-dielectric structures, all dielectrics (Mie)
- ≡ Applications: ultrahigh-resolution imaging systems, polarization optics, invisible and cloaking devices,



D. R. Smith, Willie J. Padilla, D. C. Vier, S. C. Nemat-Nasser, and S. Schultz, PRL 84, 4184 (2000)

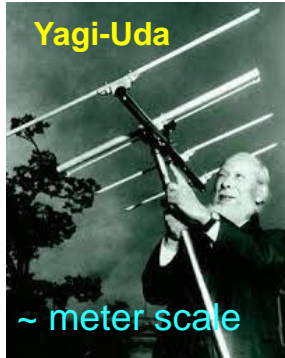


Leigh Whannell, 2020

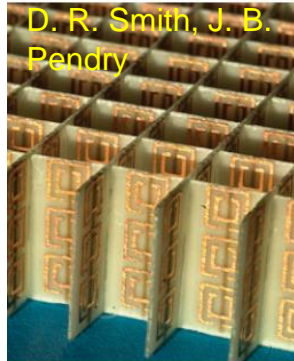


SUB-WAVELENGTH OPTICS

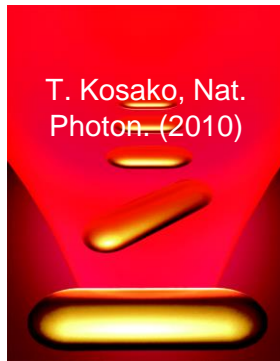
Antennas



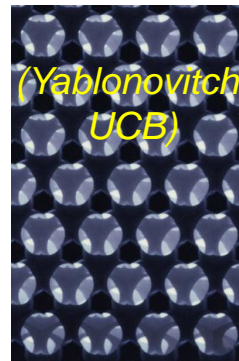
Metamaterials



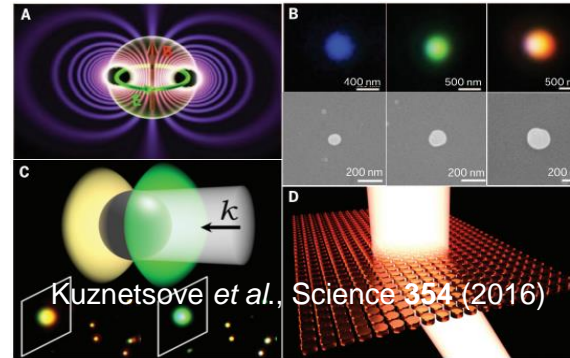
Plasmonics



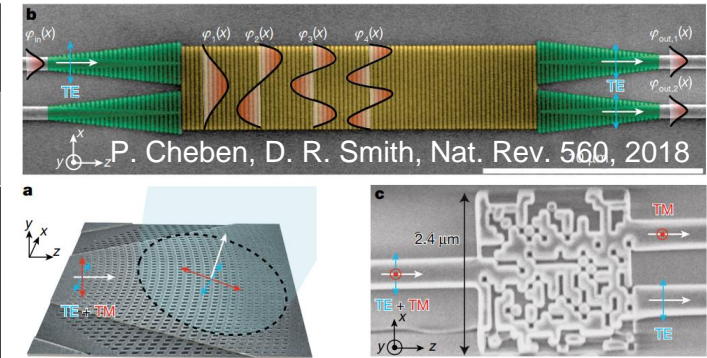
PhCs



Dielectric metasurfaces



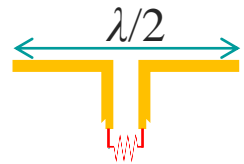
Integrated photonics



Radio

Micro

Optical frequency range



Engineering light at subwavelength scales

- ≡ Near field, far field, super resolution, spectroscopy
- ≡ Polarization, resonance controls
- ≡ Transmission, reflection, absorption, phase
- ≡ Wavefront control, beam shaping, cloaking
- ≡ Beyond classical limit (quantum)

Driven by

- ≡ New concept, theory
- ≡ Functional materials
- ≡ Fabrication, integration
- ≡ Simulation engines
- ≡ Deep learning

SUB-WAVELENGTH OPTICS

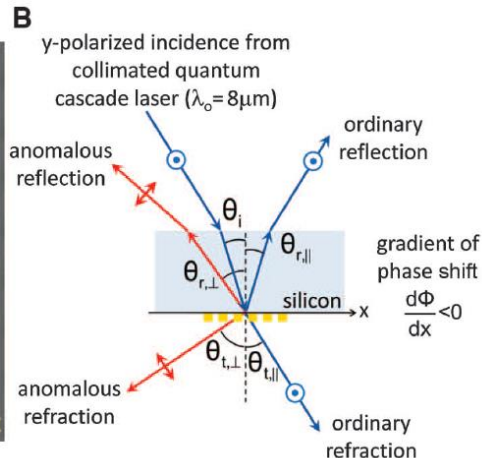
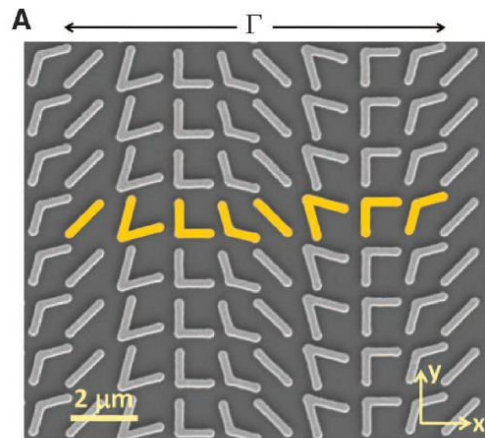
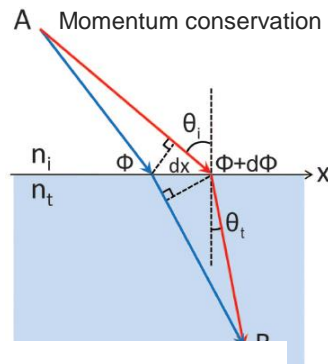
- Metasurfaces: Ultrathin metamaterials (F. Capasso, E. Hasman, V. Shalaev, ...)
- Resonance, polarization, phase, propagation, transmission reflection, refraction, absorption, ...

Generalized Snell's law for refraction

$$\sin(\theta_t) n_t - \sin(\theta_i) n_i = \frac{\lambda_0}{2\pi} \frac{d\Phi}{dx}$$

Generalized Snell's law for reflection

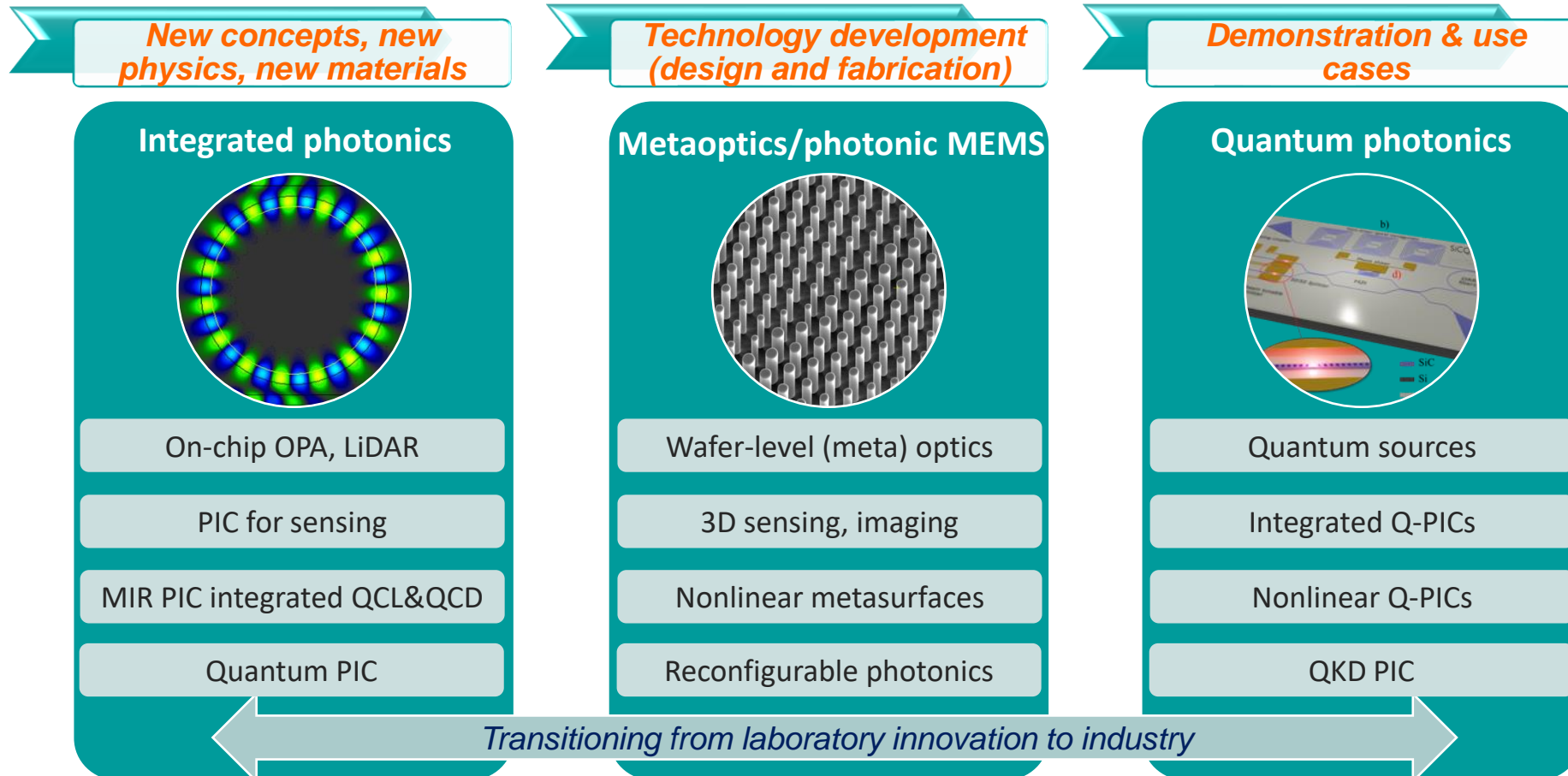
$$\sin(\theta_r) - \sin(\theta_i) = \frac{\lambda_0}{2\pi n_i} \frac{d\Phi}{dx}$$



N. Yu, F. Capasso, Z. Gaburro et al., Science **334**, 333 (2011)

WHAT WE ARE DOING

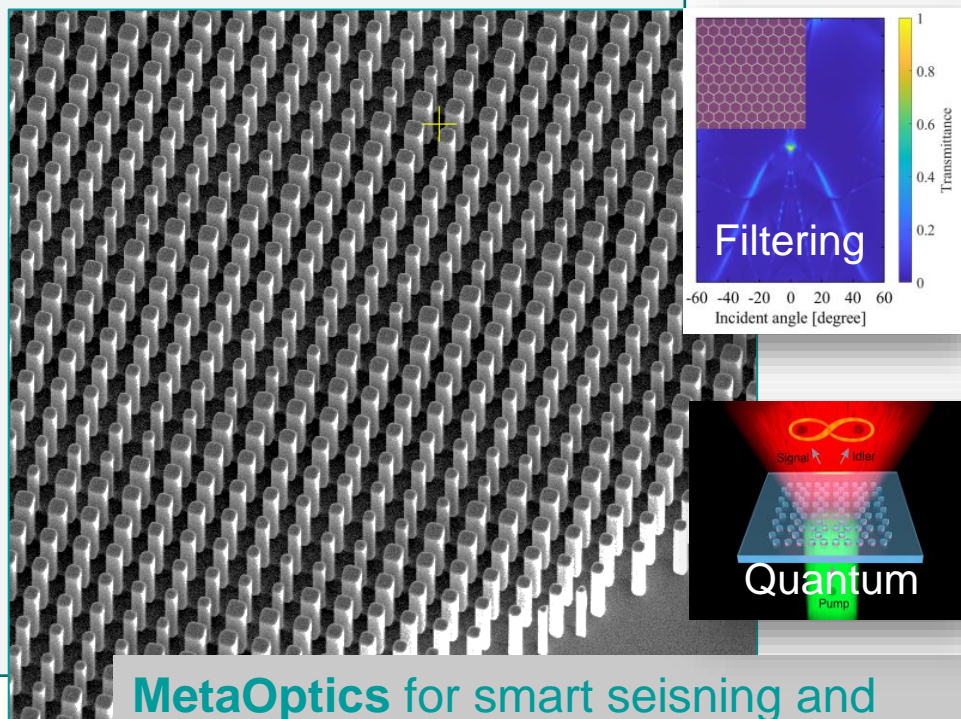
≡ Addressing critical challenges in subwavelength MetaOptics and Photonics Integrated Circuits (PICs) for diverse applications by leveraging emerging technologies & unique materials.



WHAT WE ARE DOING

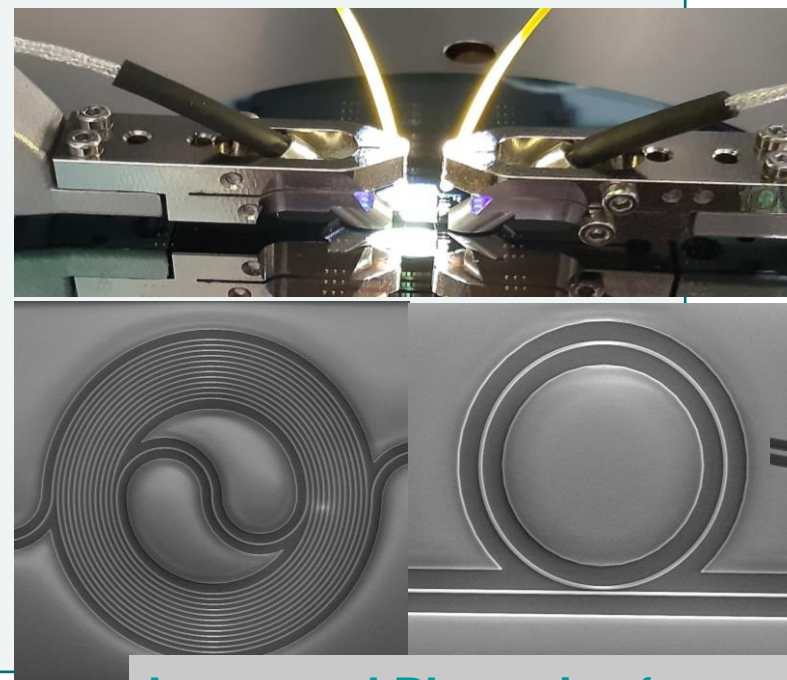
Addressing critical challenges in subwavelength **MetaOptics** and **Photonics** Integrated Circuits (PICs) for diverse applications by leveraging emerging technologies & unique materials.

MetaOptics



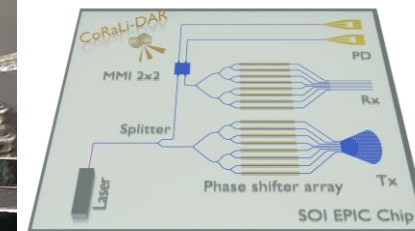
MetaOptics for smart seising and imaging devices: camera, sensor, AR, VR and quantum applications.

PIC

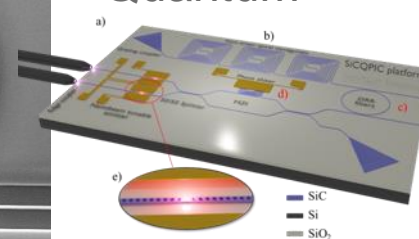


Integrated Photonics for sensing, programable photonics, LiDAR, quantum communication.

LiDAR

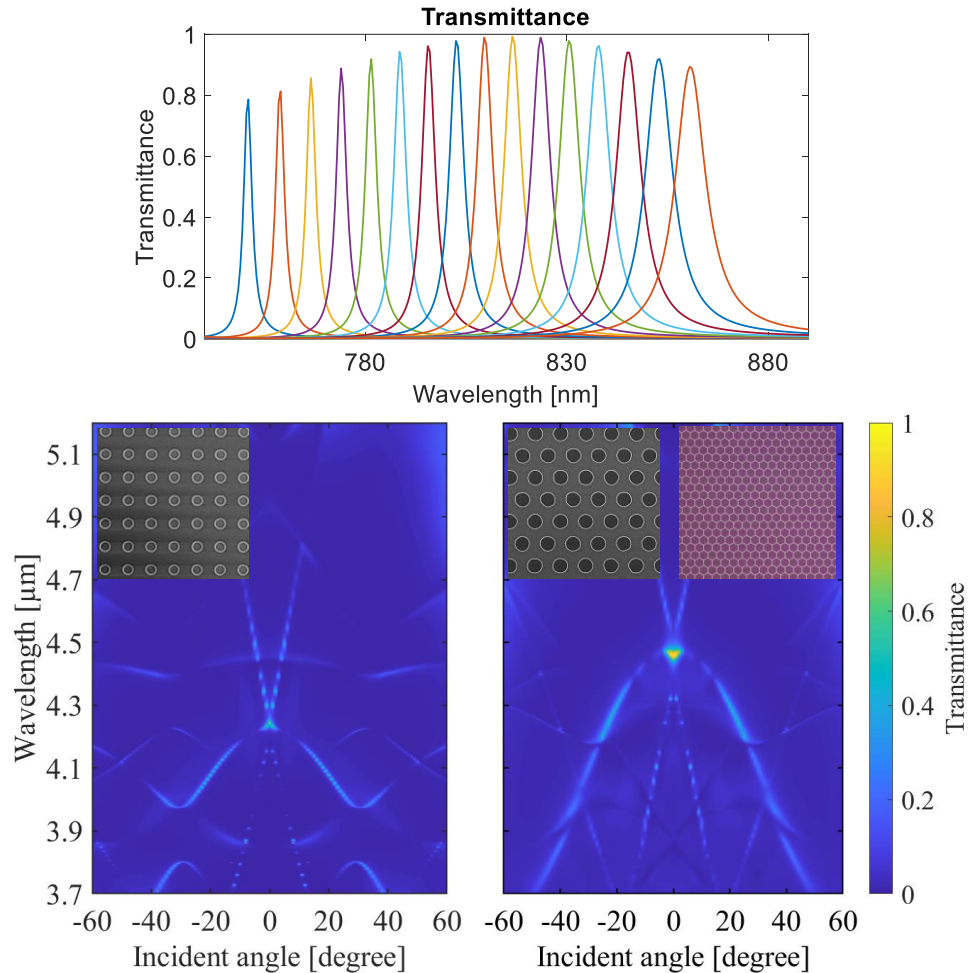


Quantum

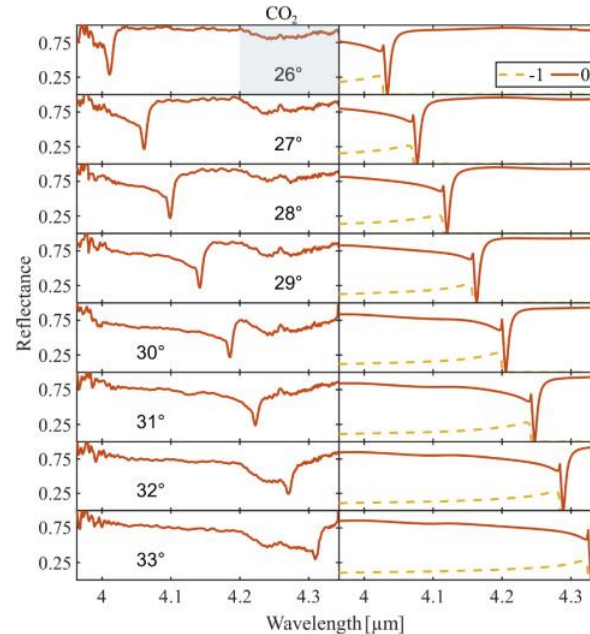
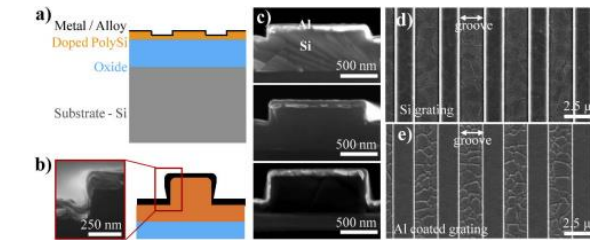


META-OPTICS FILTERS

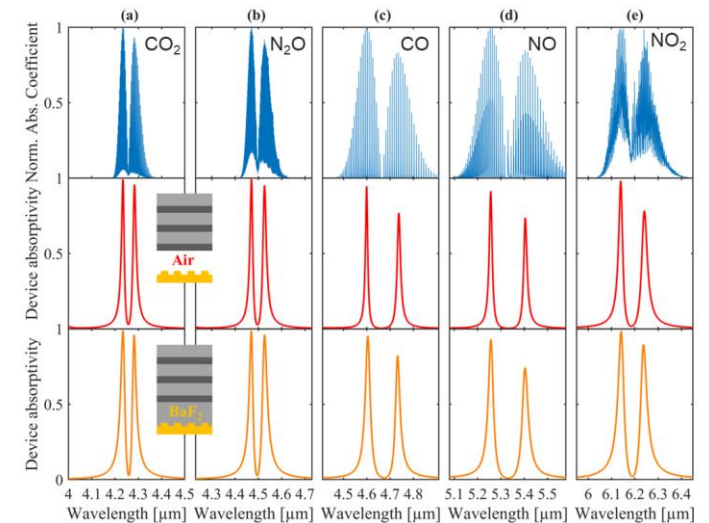
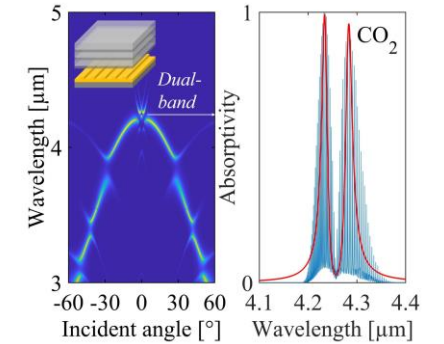
Multispectral imaging



Spectroscopic sensing



J. Spettel, Opt. Mater. Express **11**, 1058 (2021)

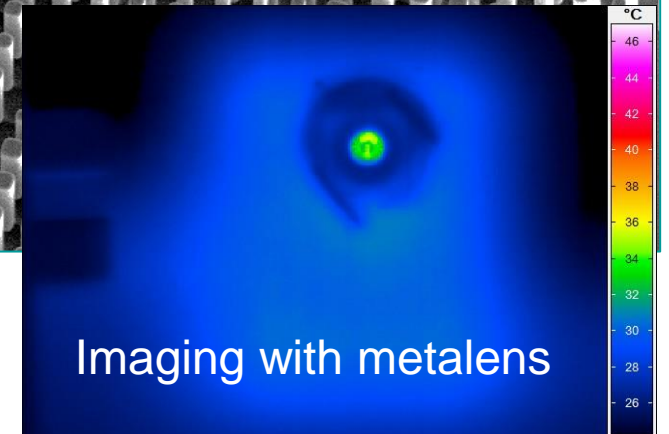
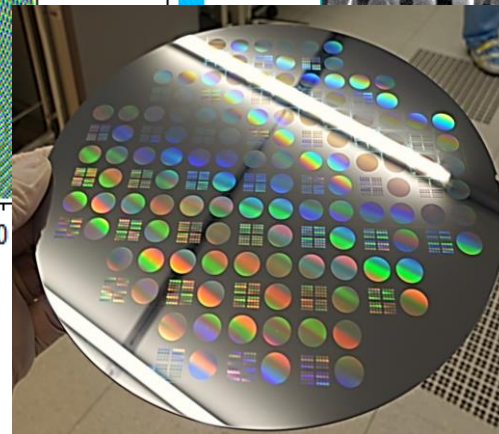
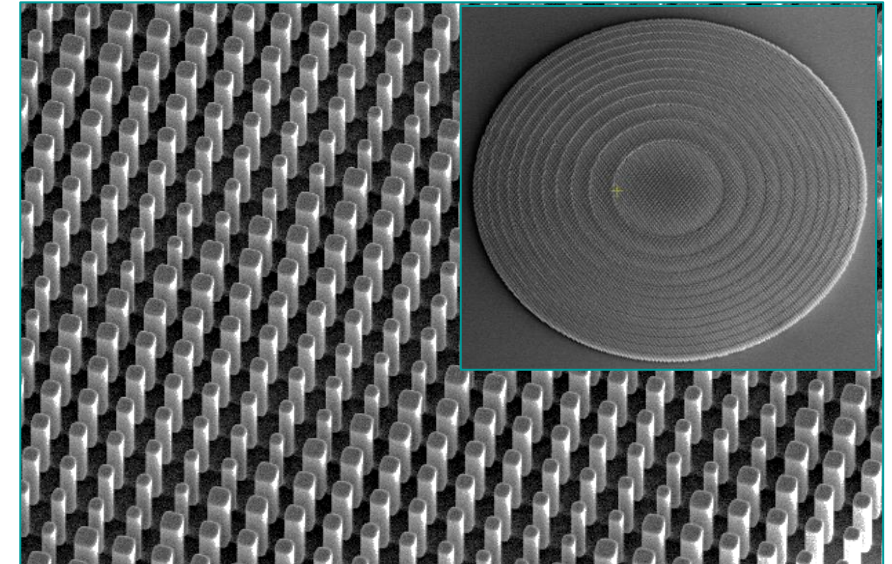
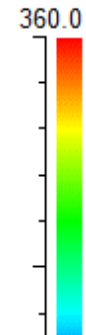
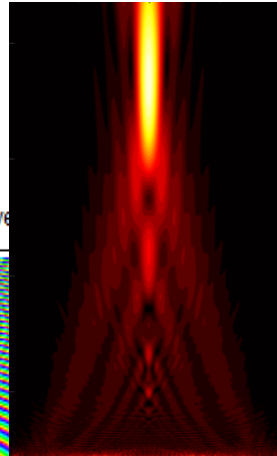
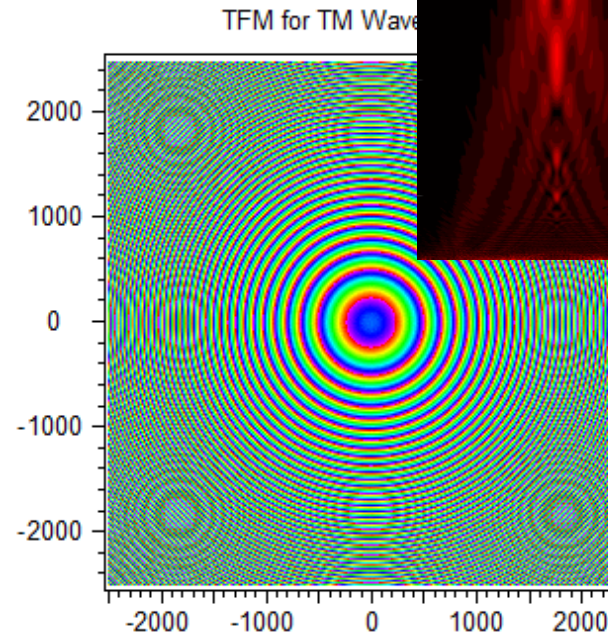
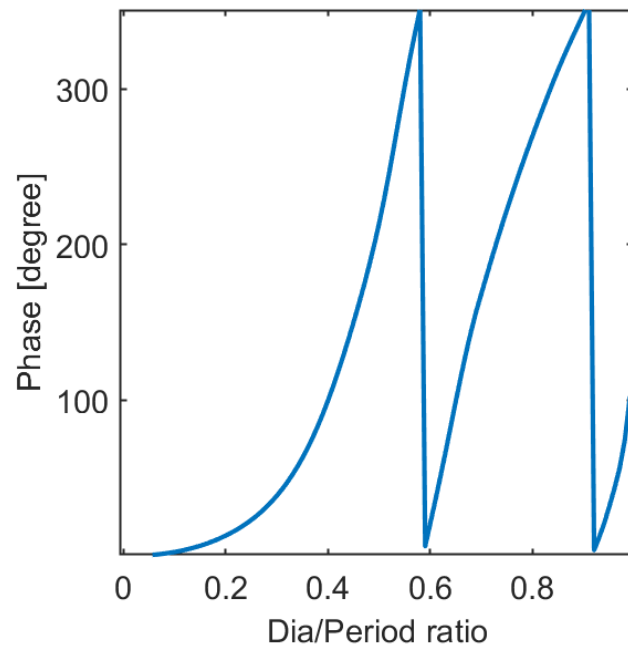


T. Dao et al. OSA Continuum **4**, 1827 (2021)

MIR METAOPTICS FOR IMAGING & SENSING

Metalenses for IR imaging

Achromatic & polarization insensitive lenses



HOW TO WORK TOGETHER

Partners	Research institutions/ universities	Tools and materials supplier	Industries/ manufactures	End-users
SAL	<ul style="list-style-type: none"> ➤ Co-develop technologies from concept to prototyping ➤ Provide reliable fabrication processes ➤ Foster collaboration with other RTOs, industry, and end-users for technology maturation ➤ Explore funding opportunities: national, EU, and bilateral proposals 	<ul style="list-style-type: none"> ➤ Collaborate to develop devices from concept to prototyping ➤ Offer complementary fabrication processes compatible with tools and materials ➤ Engage with RTOs, industry, and end-users for technology maturation ➤ Explore funding opportunities: national, EU, and bilateral proposals 	<ul style="list-style-type: none"> ➤ Partner to co-develop devices from concept to prototyping ➤ Offer complementary fabrication processes and provide feedback to improve performance and yield ➤ Collaborate with RTOs and end-users for technology maturation ➤ Explore funding opportunities: national, EU, and bilateral proposals 	<ul style="list-style-type: none"> ➤ Define device requirements and provide input throughout concept and prototyping ➤ Offer critical feedback to optimize and align solutions with market needs ➤ Collaborate with RTOs, industry, and manufacturers to drive technology maturation ➤ Explore funding opportunities: national, EU, and bilateral proposals

HOW TO WORK TOGETHER

SAL Cooperative Research

Purpose:

- Easy, accessible co-financing for R&D projects with SAL
- Long term R&D cooperations (>1year)

Organisational Framework:

- Project Evaluation by SAL
- SAL General Contract Terms
- SAL Project Agreement
- IP-rules are in line with the European State Aid Law

Advantages:

- 50% co-financing by SAL
- Bi/multilateral cooperation possible
- No application process necessary

Contract Research

Purpose:

- Technology Concepts
- Test & Measurements
- Feasibility Studies
- Proof of Concept Studies
- (Rapid) Prototyping

Organisational Framework:

- Quote – Order Process

Advantages:

- Fast project start
- No further contractual framework necessary
- Fixed price
- Clearly defined deliverables

R&D Services

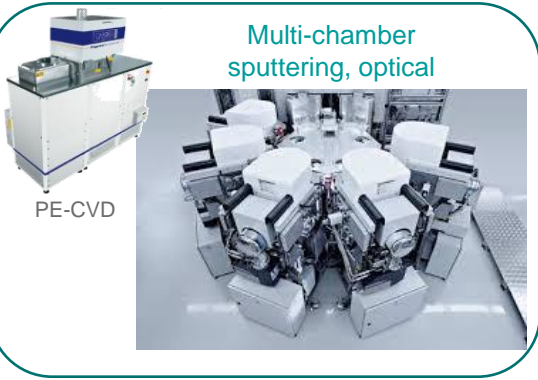
Design and simulation, characterizations, measurements and testing up to manufacturing in the field of micro- and nanotechnology.

Funded Research

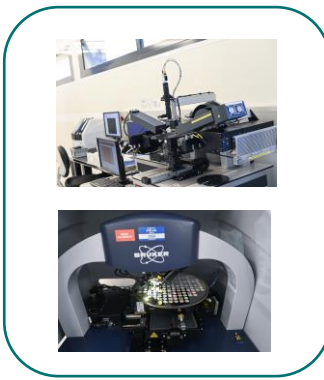


METAOPTICS FABRICATION

≡ SAL's fabrication capabilities



Functional thin films deposition



Characterization



Nano lithography

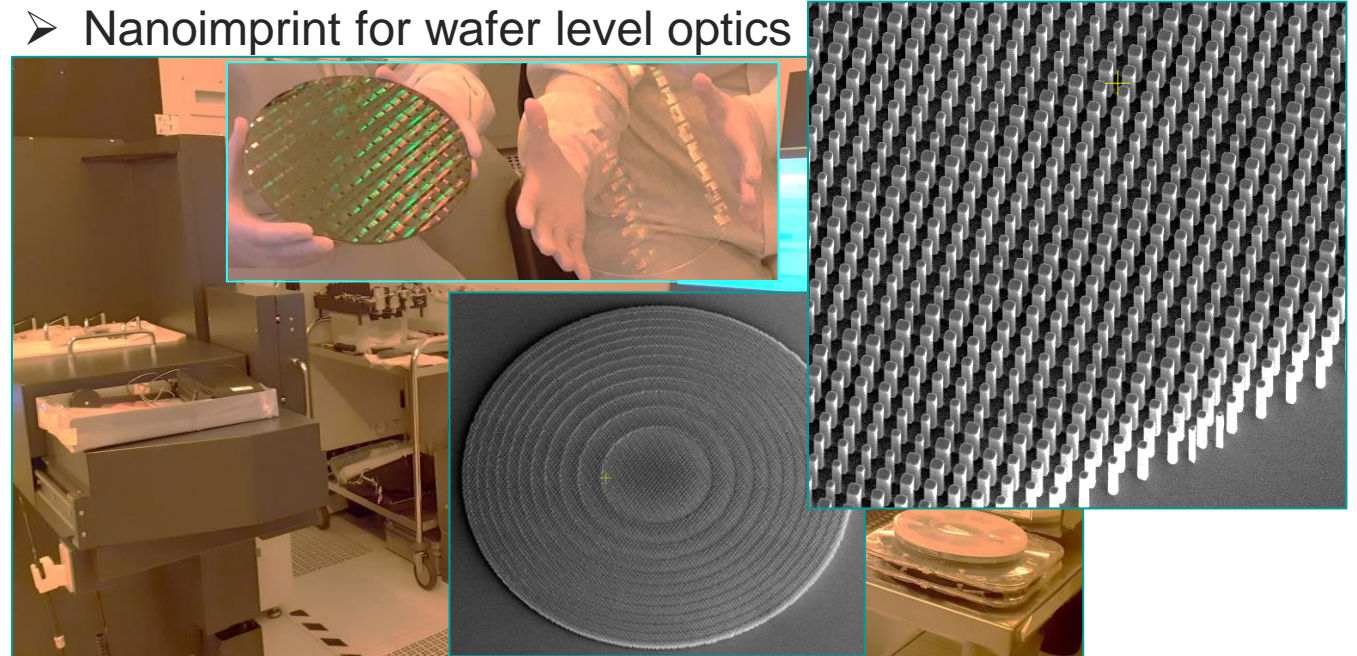
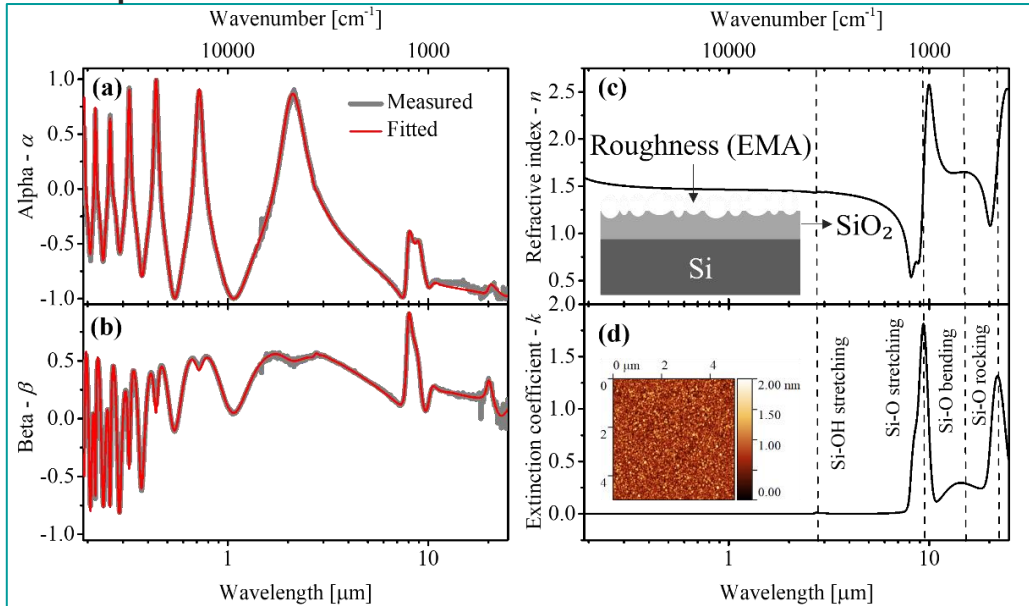


Etching (wet, dry, iso- and anisotropic)



Wafer-bonding, layer transfer

➤ Optical thin film fabrication and characterization ➤ Nanoimprint for wafer level optics



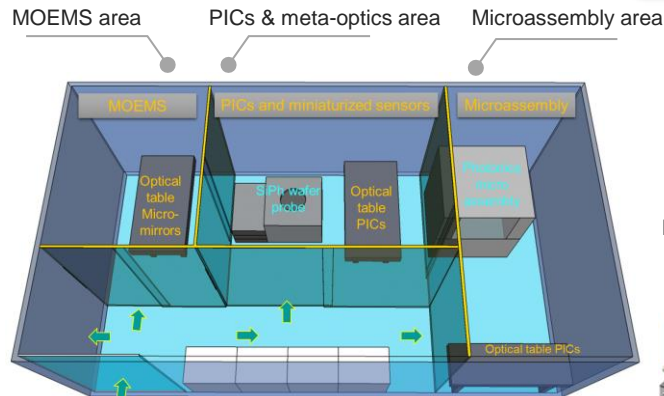
CHARACTERIZATIONS

Lab infrastructure

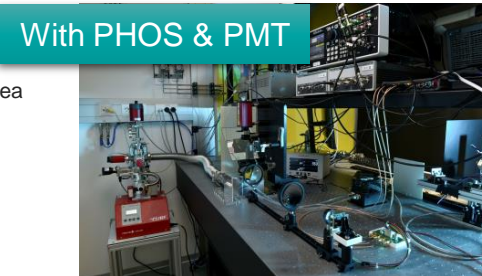
MOEMS characterization

Integrated photonics & Metaoptics

3D-photonics microassembly

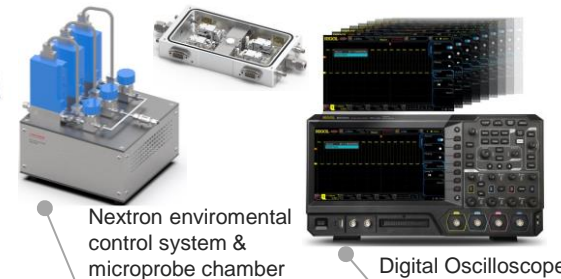


- 50-m2-ISO7 cleanroom environment
- Temperature and humidity control
- Laser safety protection



With PHOS & PMT

MOEMS characterization test bench



Nextron environmental control system & microprobe chamber

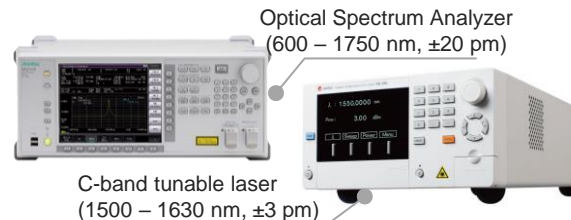
Digital Oscilloscope



12"-wafer automated photonic probe



Die-level PIC test bench



Optical Spectrum Analyzer (600 – 1750 nm, ±20 pm)

C-band tunable laser (1500 – 1630 nm, ±3 pm)

With PHOS and HIT



3D Photonic Assembly system

1. Optical MEMS (MOEMS) characterizations, test benches
2. PICs, metaoptics and miniaturized sensors characterizations, test benches
3. 3D photonic micro-assembly

1. System-level test bench for MOEMS
2. Demonstrators: Micro-projectors, micro-LiDAR, smart-lighting
3. Reliability test of MEMS & MOEMS
4. Developing solutions for MOEMS device testing and demonstration

1. Automated wafer probe for integrated photonics (PIC) characterization
2. Wafer-level optics characterization
3. System-level PIC-based sensor test bench (NIR, MIR)
4. Lab-based environmental monitoring

1. 3D Micro-assembly machine for assembly of microoptical components.
2. In-place curing and active alignment system.
3. Flipchip module and laser soldering.
4. High precision motion with sub- μm resolution.

OUTLOOKS

≡ **Metaoptics**

- ≡ Engineers light at the sub-wavelength scale
- ≡ Enhances functionalities, optical integration, and miniaturization

≡ **Progress**

- ≡ Significant advancements over the past decade
- ≡ Driven by breakthroughs in materials science, fabrication, and computational methods like deep learning

≡ **Current focus**

- ≡ Shift from an emerging field to a promising photonic technology
- ≡ Emphasis on technology maturation to meet growing application demands
- ≡ In Europe, the sector is expanding, necessitating robust collaboration among RTOs, SMEs, industries, and end-users

≡ **SAL**

- ≡ Dedicated to advancing metaoptics from design to fabrication and prototyping
- ≡ Collaboration with partners and the broader community to drive progress → Advancing metaoptics toward becoming a mature technology



Sony DADC



THANK YOU!